

10/565108

IAP20 Rec'd 19 JAN 2006
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Ken YOSHIKAWA

Application No.: New U.S. National Stage of
PCT/JP2004/009921

Filed: January 19, 2006

Docket No.: 126623

For: A METHOD FOR PRODUCING A SILICON WAFER AND A SILICON WAFER

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.